# Table of contents

**OPENING SESSION. Keynotes**

P. Perlo  
From microtechnology to nanotechnology: a “natural” evolution involving the automotive context  
E. Di Fabrizio  
Perspectives on nanofabrication and advanced Lithographies

**SESSION 1. MEMS/MOEMS & non-mechanical ultra-precision processes**

M. Rasetti  
Quantum Computation and quantum information: a new challenge for nanotechnology

B. Bläsi, V. Boerner, A. Gombert, V. Kübler, M. Niggemann, V. Wittwer  
Functional Surface-Relief Structures Manufactured by Holography and Subsequent Microreplication

M. Ille, E. Cianci, V. Foglietti, G. De Bellis, G. Caramenti  
Micromachined Chips for Biomolecular Investigation

K. Ashida, L. Chen, N. Morita  
New maskless micro-fabrication technique of single-crystal silicon using the combination of nanometer-scale machining and wet etching

G. D'Arrigo, S. Castorina, S. Coffa, C. Spinella  
Advanced Micromachining Processes for Micro Opto-electro Mechanical Components and Devices

R. Marcelli, A. Müller, F. Giacomozzi, G. Bartolucci  
Micromachined Coplanar Microwave Components: Technology and Modeling

Q. Fang, D.G. Chetwynd, J.W. Gardner  
Tensile Properties of Conducting Polymer Fibres

M. Cocuzzo, F. Giorgis, P. Civera, L. Scalrito, C.F. Pirri  
Micromachined silicon based cooling loop designed for general purpose devices

E. Cianci, A. Cianchi, V. Foglietti, A. Notargiacomo  
Diffraction Radiation by Silicon Micromachined Targets as Beam Diagnostics Instrument in Particles Accelerators

R. Kurt, D. Dumitriu, A. Karimi  
Plasma Enhanced Chemical Vapour Deposition of Patterned Cnx Films Consisting of Feathered Nanotubes

V. Foglietti, E. Cianci, D. Memmi, G. Caliano, M. Pappalardo  
Fabrication of Capacitive Ultrasonic Transducers by a Low-Temperature and Fully Surface-Micromachined Process

E. Ohmura, I. Fukumoto, I. Miyamoto  
Molecular Dynamics Analysis of Ultra Fast Laser Ablation

C.C. Wang, D.H. Chen, T.C. Huang  
Nanofabrication of Pd/Ti Nanostructured Electrodes by Electrophoretic Deposition of Pd Colloidal Dispersions

H. Takino, T. Kobayashi, N. Shibata, K. Yamamura, Y. Sano, Y. Mori  
Removal Characteristics of Plasma Chemical Vaporization Machining with a Pipe Electrode
G. Torrioli, B. Buonomo, P. Carelli, M.G. Castellano, F. Chiarello, C. Cosmelli, R. Leoni, F. Mattioli
Fabrication of a single-Electron Transistor with Mesoscopic Tunnel Junctions 62

V. Piotter, T. Schaller, R. Ruprecht, J. Hausselt
Fabrication of Micro Components by Micromachining and Injection Molding 66

H.K. Tönshoff, A. Ostendorf, K. Körber, T. Temme
Precision Machining of Optical Materials with 157 nm Excimer Laser Radiation 70

J. Remes, H. Moilanen, S. Leppävuori
The Fabrication of Submicrometer Structures in Si and Porous-Si by Focused Ion Beam 74

H. Leclerc, N. Boudeau, J.C. Gelin
Design and Modelling the accuracy of an High Precision SLS Experimental Pilot 78

E. Giovine, A. Notargiacomo, L. Di Gaspare, E. Palange, F. Evangelisti, R. Leoni, G. Castellano, G. Torrioli, V. Foglietti
Electrical Characterization of Nanowires Fabricated on a Si/SiGe 2DEG 82

E. Giovine, V. Foglietti, R. Leoni, F. Evangelisti
Fabrication of Nanowires on Si/SiGe Heterostructures by EBL 84

M. Bellucci, G. Cocorullo, F.G. Della Corte, M. Iodice, I. Rendina
High-Speed Thermo-Optical Modulation in Waveguide-Integrated Modulators 86

F.G. Della Corte, F. Cantore, M. Iodice, I. Rendina, C. Summonte
Low-Cost Chip-Integrable Silicon-Based All-Optical Infrared Light Micro-Modulator 90

Multifunctional Sensor-Chip Based on Micromachined Chamber Array 94

L. Mariucci, M. Stanizzi, G. Fortunato, V. Privitera, C. Spinella
Two-dimensional Study of Laterally Confined Ultra-shallow Junctions 98

S. Takahashi, T. Miyoshi, Y. Takaya, R. Nakajima
Nano-defects Detection of Si Wafer Surface Using Evanescent Light - Computer Simulation by Means of FDTD Method 102

G. Amato, L. Boarino, S. Borini, A.M. Rossi, V. Lysenko
Micromachined integrated Si/Al Thermopiles Based on Porous Silicon 106

G. Manzoni, F. De Bona, E. Di Fabrizio
Design and Fabrication of a Microvalve for Space Applications 110

A. M. Rossi, G. Amato, L. Boarino, D. Madonna Ripa, E. Monticone, S. Borini
Ultrasound generator based on porous silicon 114

G. Amato, L. Boarino, A. M. Rossi, S. Borini, G. Lulli, A. Parisini
Silicon On Insulator wafers and devices from High-Energy Implantation and Electrochemical Etching 116

Session 2. MEMS/MOEMS & material properties 119

R.W. Whatmore
Ferroelectric Materials and their Applications in Microsystems and Nanotechnology 120
IX

N. Savalli, S. Baglio, M. Scalora, M. Bloemer
Opto-Electro-Mechanical Systems based on "Transparent Metals" 124

H.K. Tönshoff, K. Körber
Comparison of Laser Processes to Achieve Conductive Surface Areas on Ceramics 128

H. Bohlmann, H. Liegerer, R. Götzen, A. Reinhardt,
Micro RP&M Technologies for End User Applications 132

A. Chilkoti, J. Hyun
Surface-Initiated Free Radical Polymerization of Polymer Microstructures on a Self-Assembled Monolayer on Gold 136

K. Kuwahara, Y. Watanabe, M. Ota
Rotational Characteristics of Laser Opto-Microactuator Controlled by Magnetic Force 140

D. Bethmont, A. Karimi
Mechanical Properties at Submicro Scale by Nanoindentation 144

M. Weck, B. Petersen
Adhesion Problems During Handling of Micro parts – Vibration Assisted Release of Objects 148

T. Sumomogi, M. Nakamura, T. Endo
Simultaneous Evaluation of Surface and Subsurface cracks on Nanoscale Machined Brittle Materials by Scanning Force Microscope and Scanning Laser Microscope 152

D. Reyes, H.D. Tran
Design and Evaluation of a MEMS Dynamometer 156

E. Westkämper, B. Gottwald, P. Klein, A. Gemmler
Modelling of Crystal Growth for Sputtered Layers by Molecular Dynamics 160

Torii, A. Ueda, S. Okuma
A small Coil Used for Displacement Measurement 164

Y. Kanda, M. Suzuki
An Attempt at Micro Cutting under Different Cutting Environment Using AFM 168

A. Notargiacomo, V. Foglietti, F. Evangelisti
Nanoscale Patterning of Thin Aluminum Film Using AFM Lithography 172

R. Liedtke, G.P. Lopez, H.D. Tran
Microwriting Using Surface Tension 176

S.Y. Lee, Y.B. Choi, K.K. Park, Y.S. Jo, S.G. Lim, S.W. Kim
Grating Projection Moiré Interferometry for High Speed 3-D Inspection of Meso-scale Objects 180

R. Neugebauer, A. Schubert, J. Böhm, T. Burkhardt
Forming Technologies for Production of Micro Structured Parts 184

D.L. Corker
Rapid Material Analysis for Determining the Effect of Piezoelectric Dopants and Alternative Material Preparation Techniques 188

F. Pérennès, F. De Bona, F.J. Pantenburg
Microfabrication with Deep X-ray Lithography: Technological Aspects Affecting the Microstructure Geometry 192

M. Heckele, A. Durand
Microstructured Through-Holes in Plastic Films by Hot Embossing 196

A. Chilkoti, W. Frey
Ultraflat Nanosphere Lithography: A New Method to Fabricate Flat Nanostructures 200
SESSION 3. Metrology & nanometrology I

E. Spanner, J. Thiel,
Homodyne Laser Interferometer with new Interferometer Optics and Fiber – Coupled Measuring Head for Ultra Precision Measurement Below 1 nm 222

K.M.-Hagen, M. Wolf, A. Abou-Zeid
Measuring Micrometer Steps with Nanometer Resolution 226

S.-Woo Kim, H.-G. Rhee
Phase Measuring Volumetric Interferometry for Three-Dimensional Coordinate Metrology 230

T. Ruijl, J. Franse, J. van Eijk
Ultra precision CMM Aiming for the Ultimate Concept 234

J. Dankowski
State of the Art Vibration Isolation of Large coordinate Measuring Machines with an Adverse Environment 238

J. Dankowski
State of the Art Vibration Isolation Internal to Large Aerospace Vacuum Chambers for Space Simulation Testing 242

R. Furutani, C.Y. Won
High Resolution Probe System for CMM 246

P. Kappelhof, B. Snijders, C. Braam, H.J.P. Vink, P. Verhoeff, B. Calvel, F. Safa
GAIA OPD Testbench. Interferometer with Tens of Picometre Accuracy 250

Y. Tanaka, Y. Hirai, M. Kabuto, K. Kawabata, H. Haga, M. Nagayama
Evaluation of Viscoelasticity of Biological Cells in Liquid by Atomic Force Microscope 254

K. Wendt, H. Schwenke, F. Wäldele, M. Krawczyk, K. Kniel
Error Mapping of Large CMMs by Sequential Multi-lateralation Using a Laser Tracker 258

J.G. Salsbury, R.J. Hocken
A Novel Step Plate Gage for Machine Metrology 262

S. Cao, W. Hoffmann, U. Brand, T. Kleine-Besten, P. Pomnoppadol, S. Büttgenback
A Micro Probing System for Dimensional Metrology on Microsystem Components 266

T. Eom, T. Choi
Single Frequency Laser Interferometer with Subnanometer Accuracy 270

T. Eom, D. Chung
Precision Goniometer System with Indexing Table and Small Angle Measuring Interferometer 274
S. Driessen, C. Bosbach, T. Pfeifer, B. Michelt
Fiber-optic Interferometer for Absolute Distance Measurements with High Measuring Frequency 278

A. Bai, F. Bitte, T. Pfeifer
Assessment of Interferometer-errors with the Virtual Interferometer 282

A. Lassila, J. Unkuri
Investigation of Nonlinearity of Gauge Block Interferometers 286

G. Jäger, E. Manske, T. Hausotte
Nanopositioning and Measuring Machine 290

B. Bodermann, V. Burgarth, A. Abou-Zeid
Modulation-free Stabilised Diode Laser for Interferometry Using Doppler-reduced Rb Transitions 294

H. Matsuoka, S. Kasei
Measurement of Form deviations of Minute Module Gears 298

Design Aspects of the international Line Scale Comparison Nano3 302

Evaluation of Thermal Drift of Nano-CMM 306

E. Canuto, F. Bertinetto
The use of Fabry-Pérot Interferometer for Ultra Fine Dimensional Control 310

E. Canuto, A. Rolino, P.P. Pepe, F. Bertinetto, P. Cordiale
Digital Control of the Frequency of Laser Sources for Fine Metrology 314

E. Canuto, A. Rolino, P.P. Pepe, F. Bertinetto, P. Cordiale
Fine Digital Temperature Control for Metrological Applications 318

M.N. Bournachev, Y.V. Filatov, D.P. Loukianov, P.A. Pavlov, A.E. Sinelnikov
Reproduction of Plane Angle unit in Dynamic Mode by Means of Ring Laser and Holographic Optical Encoder 322

R. Probst, M. Krause
Six Nanoradian in 2π Radiant - A Primary Standard for Angle Measurement 326

R. Haberland, H. Mu
Instabilities in High Speed Scanner Air Bearings 330

M. Bisi
Sub-micrometer resolution Position Sensor for Use in Active Equipment for Vibration Isolation 334

V. Burgarth, A. Abou-Zeid
Wavelength Stabilized Diode Laser Interferometer for Calibration of Length Measuring Instruments 338

S. Weikert, W. Knapp
The Grid-bar, a New Device for Machine Tool Testing 342

R. Meneghello, L. De Chiffre, A. Balsamo
Precision of Coordinate Measurements in Industry: AUDIT ITALIANO 346

J. Zuo, M.A. Mannan, A.N. Poo
A Real -Time Contouring Error-mapping System in an Open Architecture PC Based Controller Environment 350

E. Savio, L. De Chiffre
An Artefact for Traceable Free Form Measurements on Coordinate Measuring Machines 354

F. Meli
International Comparison in the Field of Nanometrology: Pitch of 1D gratings (Nano4) 358
E. Savio, L. De Chiffre  
Performance Verification of CMMs for Free Form Measurements 362

A. Piratelli-Filho, B.D. Giacomo  
Development of CMM Volumetric Performance Test Utilizing Ball Bar Gauge 366

E. Ricci, M. Verdi, J. Valero Català  
A Large CMM Under Harsh Temperature Conditions: a real case 370

S. Desogus, G.B. Picotto, M. Pisani, B.I. Rebaglia  
A probe with differential capacitive readings of displacements 374

E. Canuto, S. Tonani  
Digital stabilization of a suspended table for fine metrology 378

D. Sinigalliesi  
Dimensional Measurement of Hard-Disk-Drive Suspensions 382

SESSION 4. Metrology & nanometrology II 387

C. Evans, A. Davies, T. Schmitz, R. Parks, L.-Z. Shao  
Interferometric Metrology of Substrates for VLSI 388

J. Haycocks, K. Jackson  
A Metrological Atomic Force Microscope for Calibration of Transfer Standards 392

K. Hasche, K. Herrmann, M. Krumrey, S. Schädlich, W. Frank, M. Procop, G. Ulm  
Calibrated Reference Standards for Films in the Nanometer Range 396

F. Lamarque, J. F. Le Gargasson  
Confocal Scanning Video Endoscope 400

G.B. Picotto, M. Pisani  
A metrological SPM for dimensional surface measurements 402

O. Jusko, R. Liang, M. Neugebauer  
Design and Implementation of an Advanced Dynamic Probe Calibrator for Form Measurement Instruments 406

C. Lupi, D. Leduc, P. Blanchard, R. Le Ny, G. Normand, C. Boisrobert  
High Resolution Low Coherence Reflectometry Defect Localisation and Analysis 410

R. Leach, I. Garbutt, P. Harris, M. Cox  
Sinusoidally Modulated Reference Artefacts for Calibration of Surface Texture Measuring Instruments 414

K.A. Tiftikci, C. Velzel, P.H.J. Schellekens, F. Bitte  
Design Aspects of a Fast 3D Surface Scanner Based on DMD Technology and Confocal Microscopy 418

M.R.H. Kraus  
Discrete Measurement Data Analysis: a New Method to Characterize Structured Surfaces on Atomic Scale 422

U. Berzano, G. Durando, E. Massa  
Phase Contrast Imaging Using an X-Ray Interferometer 426

W. Gao, P.S. Huang, T. Yamada, S. Kiyono  
Flatness metrology of Large Silicon Wafer Using an Absolute Error Separation Technique 430

O. Hignette, P. Cloetens  
Metrology and Manufacturing of Coherence Preserving Synchrotron X-Ray Optics 434
K. Herrmann, K. Hasche, F. Pohlenz, R. Seemann
Determination of the Geometry of Various Indenter Types Used for Micro and Nanoindentation 436

H. Fukatsu, Y. Nakanishi, K. Asahina, S. Hirai
Noncontacting Surface Roughness Measurement using the Optical Stylus Method 440

K.C. Kim, J. Woo Seo, D.K. Kang, D.G. Gweon
Correction of distortion in Confocal Scanning Laser microscopy 444

S.Q. Lee, K.S. Moon, D.G. Gweon
The Effect of Stereo Focus Technique on the Three-Dimensional Imaging in the Confocal Scanning Microscopy 448

K. Yanagi, T. Kurozo, A. Shimamoto
Development of a Sophisticated Scanning Instrument for Surface Topography Measurement Using an Optical Flat as a Reference Plane 452

X. Liu, Y. Gao, Z. Li
A Functional Noise-Immune Unwrapping Method Based on Wrapped Phases Statistics and Self-Calibration 454

X. Liu, Y. Gao, M. Chang
A New Lateral Shearing Interferometric Measurement Method for Aspheric Lenses under the condition of Vibration 458

T. Doi, T. Kurosawa
Accurate Optical Surface Profilometer Based on Mirau-type Interferometric Microscope 462

G. Barbato, G. Brondino, M. Galetto, A. Germak
Uncertainty Evaluation for Martens Hardness. Analysis of the Velocity Effect 466

J.R. Pratt, D. Newell, E. Williams, D. Smith, J. Kramar
Towards a Traceable Nanoscale Force Standard 470

I. Misumi, S. Gonda, T. Kurosawa
Precision Measurements of 1 D Grating Using Metrological Atomic Force Microscope 474

M. Schulz, I. Weingärtner
Measurement of Steep Aspheres by Curvature Scanning: an Uncertainty Budget 478

K. Schneefuss, T. Pfeifer
Microscopic Formtesting of Large Area Microstructured by Means of Formtesting Interferometry 482

A. Bai, K. Schneefuss, T. Pfeifer
Nulltest for Aspherical Microlenses Using Moiré Deflectometry 486

C. Dal Savio, T. Dziomba, T. Sulzbach, O. Ohlsson, H.U. Danzbrink
Scanning Near-field Optical Microscopy with Silicon Cantilever Probes 490

I.M.R. Najjar, D.G. Chetwynd
Surface-Related Characterisation in Contact-Probe Metrology 492

A. Yacoot, L. Koenders, U. Kuetgens, T. Weimann
A Combined X-ray Interferometer and Scanning tunnelling Microscope for the Characterization of Grating Structures 496

L. Jung, R. Krüger-Sehm, B. Spranger, L. Koenders
Reference Software for Roughness Analysis 500

V. Greco, G. Molesini
Absolute Calibration of Optical Flats: Long Term Reproducibility of Interferometric Measurements 504
X. Liu, F. Gao
Multi-function evaluation of Surface at Micro/Nano Scales by a New Tribological Probe Microscope 508

Intercomparison of Scanning Probe Microscopes 510

J. Gæmaes, A. Kühle, N. Kofod
Treceable Stepheight and Roughness Measurements with Atomic Force Microscopes 514

H.J. Pahk, Y.M. Hwang
A New Method for Three-Dimensional Measurement of Surface Profile Based on the Focused Image Surface Algorithm and Optical Microscope 518

F. Cabiati, V. D'Elia, D. Serazio
Vector Transducer for Precision Offset and Tilt Monitoring Suitable to Levitated Objects 522

M. Strobl, W. Treimer, A. Hilger
Experiments with Tuneable Many Bounce Channel Cut Crystals for Thermal Neutron Scattering 526

Calibration standards for the in-situ determination of AFM tip-shapes 530

Y. Joulin, O. Parriaux, F. Pigeon, M. Bonis, Y. Alayli, S. Topçu
Double Read Head for the Measurement of Differential Effects on a Grating Scale 534

SESSION 5. Ultra-precision motion control 539

Y. Yoshimura, F. Hatori, Y. Ue, H.Takahashi
On Displacement Characteristics of One-piece XYZ Table for Fine Positioning 540

D. Reynaerts, H. Van Brussel, F. Al-Bender, M. Versteyhe, S. Devos
Construction and Control of an Ultra-stiff Nanopositioning System 544

J. Flügge, G. Dai, R. Köning
Software and Control System of the PTB Nanometer Length Comparator 548

S. Fukada
Microscopic Behavior of Preloaded Ball Screw for Ultra-precise Positioning with Nanometric Resolution 552

V.I. Rakhovsky, S.V. Vakula,
Precision Alignment of Fiber Optics Assemblies by Using a Novel "Super Precise" Nano Positioning System 556

J.Y. Shim, H.W. Jung, D.G. Gweon
Modelling and Control of the Multi-axis Nanopositioner Using Inertial Slider/Walking Method 558

S. Li, Z. Zheng, Y. Dai
The Design of a High Precision Tracking Controller Used in Ultra-precision Machine 562

J.S. Chen
Dual-Mode Friction Compensation of a Precision Linear-Motor Rolling-Guide Stage 566
<table>
<thead>
<tr>
<th>Title</th>
<th>Page</th>
</tr>
</thead>
<tbody>
<tr>
<td>Hybrid Vibration Control of Slide Carriage of Ultraprecision Machine Tool</td>
<td>570</td>
</tr>
<tr>
<td>A Micro-Manipulator for Scanning X-Ray Interferometry</td>
<td>574</td>
</tr>
<tr>
<td>Optimal Design of XY0 Precision Positioning Stage Maximizing the System Bandwidth</td>
<td>578</td>
</tr>
<tr>
<td>An Alternative Static Friction Control Algorithm for Precision Motion Control of Mechanical Drivers</td>
<td>582</td>
</tr>
<tr>
<td>A Lead Screw Stepper Equipped with Piezo Driven Ultra-high Resolution Linear Positioner</td>
<td>586</td>
</tr>
<tr>
<td>Auto-alignment Algorithm for Near-Field Optical Recording Head</td>
<td>590</td>
</tr>
<tr>
<td>Precision Flexure Hinge Mechanism Using the Elastic Modelling Method</td>
<td>594</td>
</tr>
<tr>
<td>Velocity of Precision Positioning Miniature Robots Using Piezoelectric Elements and Electromagnets</td>
<td>598</td>
</tr>
<tr>
<td>Calibration Aspects of a Measurement System for an Ultra-stiff Nanopositioning System</td>
<td>602</td>
</tr>
<tr>
<td>Investigations of Alignment and Positioning Principles for Optical Detectors</td>
<td>606</td>
</tr>
<tr>
<td>Voice coil actuator for active vibration isolation in microgravity</td>
<td>610</td>
</tr>
<tr>
<td>Active Magnetic Suspension for Satellite Inertial Wheels</td>
<td>614</td>
</tr>
</tbody>
</table>

**SESSION 6. Mechanical ultra-precision processes**

<table>
<thead>
<tr>
<th>Title</th>
<th>Page</th>
</tr>
</thead>
<tbody>
<tr>
<td>Tetraform 'C' - A Major Advancement in the Efficient Machining of Optical Surfaces on Hardened Steels</td>
<td>620</td>
</tr>
<tr>
<td>Cutting tools and material conditioning for micro end milling of tool steel</td>
<td>624</td>
</tr>
<tr>
<td>Advanced Cutting Tools for Precision Machining of Steel</td>
<td>628</td>
</tr>
<tr>
<td>Investigation of Single Asperity Microcutting using an Atomic Force Microscope</td>
<td>632</td>
</tr>
<tr>
<td>Creation of Ultraprecision Microgrooves Using Non-Rotational Cutting Tools</td>
<td>636</td>
</tr>
<tr>
<td>Kinematics and Material Removal Mechanisms in Ultrasonic-Assisted Diamond Turning of Brittle Materials</td>
<td>640</td>
</tr>
</tbody>
</table>
G.J. Pietsch, M. Kerstan
Simultaneous Double-Disk Grinding - Machining Process for Flat, Low-damage and Material-saving Silicon Wafer Substrate Manufacturing 644

S. Lavrynenko
Testing of Surface Generation Process of Polymer Optics by Single-point Diamond Micromachining 648

H. Hashizume, H. Yoshioka, H. Shinno
In-Process Monitoring of Thermal Behaviour near the Cutting Point during Ultraprecision Machining 652

F. Klocke, D. Pähler, A. Jakob
Precision Machining of Future Silicon Wafers – Grinding and Slicing Techniques for Flawless Qualities 656

I. Nakamura, M. Sato, T. Tanaka, H. Seki, M. Ishiyama
Dinamic FEM Analysis of Micro Groove in Nanometer Order Prepared by Ruling Engine 660

K.E. Puttick, A.G. Mamalis, S. Lavrynenko
Registration and Modelling of Polymers Stress Propagation in Controlled Directional Fracture Processes by Microcutting and Indentation 664

X. Wang, S. Jiang, C. Liu, Z. Shi, D. Wu
The Study on Diamond Precision Turning Technology of Middle-Convex and Varying Ellipse Piston 668

H. Onikura, B.K. Shil, O. Ohnishi, R. Inoue, T. Semba
Fabrication of Micro Cylindrical Diamond Grinding Tools by Ultrasonic Vibration Grinding for Drilling of Brittle Materials 672

Small Tolerances & Large Areas: Micromachining Meets Industrial Requirements 676

E. Brinksmeier, W. Preuss, A. Gessenharter
Manufacturing of Calibration Standards by Diamond Machining 680

Y. Gao, Z. Tao
Tests of Flow Patterns of Grinding Coolant Interfered using an Injection of Stream 684

T. Kaneeda, S. Yokomizo, D. Nishiyama
Transmission Electron Microscopy of Oxygen-Free Copper Machined Surface 688

Y. Liang, X. Luo, S. Dong, K. Cheng
An MDS Study of the Micro-vibration effects of Diamond Tools Roughness on Surface 692

Z. Zhong, S.H. Yeo, L.K. Tay
A Study of Relationship between Roughness and Lightness of Precision Machined Surfaces 696

X.D. Liu, L.C. Lee, F.Z. Fang, S.K. Lau, P.S. Chan
Shrinkage Error Compensation of Plastic Lenses by Modifying Mold Inserts Using Diamond Turning 698

L. Kudla
Strength Properties of Miniature Drills 702

E. Uhlmann, H. Engel, R. Hammer, C. Paesler
Impact of Diamond Geometry on Removal Mechanisms During Machining of GaAs 706
Y. Kobayashi, K. Shirai
Surface Texturing on a Microscopic Area by Micro-cutting 710

M. Takacs, I. Meszaros, B. Vero
Surface Integrity by Micromilling of Polycrystalline Metals 714

J. Nyirő, A.G. Mamalis, J. Prohászka, I. Mészáros
Analysis of Ultraprecision turned Mirror Surfaces 718

H.H. Gatzen, C. Morsbach, M. Tricard
Dual Wheel Miniature Gang for Silicon Wafer Dicing 722

C.R. Pagotto, J.G. Duduch, R.G. Jasinevicius, A.J.V. Porto
Investigation on the Plasticity of Window Glasses at Room Temperature Using Vickers Micro-Indentation and Single Point Diamond Turning 726

H. Khanfir, P. Revel, R.Y. Fillit
Influence of the Cutting Parameters and Crystallographic Orientation on the Surface properties of Ductile Materials in Ultraprecision Machining 730

M.A.J. van As, M. de Jongh
The manufacturing of high NA objective lenses for optical storage 734

T. Kuriyagawa, M. Saeki, K. Syoji
Study of Electrorheological Fluid-Assisted Ultra-Precision Polishing For 3-Dimensional Small Parts 738

F. Klocke, S. Hambucker
Influence exerted by the pad material and polishing suspension on reproducibility of a polishing process 742

S. To, W. B. Lee, C.F. Cheung
Investigation of surface properties in ultra-precision diamond turning 746

C.F. Cheung, W. B. Lee
Prediction of nano-surface generation in ultra-precision diamond turning from a new materials induced vibration model 750


T. Moriwaki
Recent Development in Ultraprecision Machine Tool Technology 756

M. Takahashi, T. Masaki, D. W. Davis, C. Stroshine
Development of Laser Printer Free Form Mirror and Related Machining and Metrology Systems 758

Accuracy-influencing Factors Analysis and Error Resources Identification in Ultra Precision Machining 762

M. Weck, B. Leifhelm

L. Phee, C. Stefanini, A. Arena, D. Accoto, A. Menciassi, G. Pernorio, M. Boccadoro, P. Dario
Mechanical Clamping Mechanisms for Locomotion in the Gastrointestinal Tract 770

G. Jayaraman, V.K. Venkateswaran, K. Niranjan Reddy
An Analytical Approach for Precise Positioning of Tool in Diamond Turning 774

T. Pfeifer, G. Dussler, S. Driessen, M. Weck, B. Petersen
Assembly of Micro Systems by the Example of Miniature Flexible Fibre-scopes 778
S. Zelenika, F. De Bona
Analytical and Experimental Characterisation of High-Precision Flexural Pivots 782

A. Weckenmann, R. Ernst, R. Hornfeck
Tolerancing of Micromechanical-Monolithic Components 786

T. Goto, S. Asano, O. Hasegawa, T. Tsuno
Development of a Rotary Fast Tool Servo for Ultraprecision Grinding of Silicon Wafer 790

Y. Dai, X. Peng, S. Li
Analysis and Elimination of Servomechanism Error Source Measuring on an Ultra-precision Lathe 794

S. Li, Y. Liu, Y. Dai
Research on Precision & Ultra-precision Machining Center-oriented Workpiece Geometric Localization Algorithms 798

S. Kaji, T. Goto, O. Hasegawa, T. Tsuno, S. Asano, T. Kurimoto
Ultraprecision Grinding of Large Silicon Wafer Using a Rotary Fast Tool Servo 802

M. Ono, E. Arakawa, S. Kyomine, S. Kato
Fabrication of a Microrobot Movable in a Freely Held Pig's Small Intestine 806

R. Haberland
Machine vibration and machined surface 810

J.L. Vavrille and Club Nanotechnologie Workgroup 2
Progress on the French National Intercomparaison of Precision Turning Machines 814

M. Schöpf
Trueing and Dressing of High Precision Grinding Tools with Unconventional Machining 816

M. Schöpf, G. Burkhard
New Replication Method for the Evaluation of the Surface Topography of Grinding Tools 820

S.W. Kim, T. Keem, S. Yoo
Active Thermal Stabilization of Machine Structures Using the Fixed Temperature Point of Gallium 824

R.F.M. Marcal, A.A. Susin, J.L. Kovaleski
Detecting Incipient Faults in Rotating Machines with Vibration analysis and Fuzzy Logic 828

J.S. Ahn, S.M. Kim, S.K. Lee
Micro Machining Using an Electro Magnetic Exciter 832

E. Egerer, U. Engel, G. Van Der Heyd
Handling of Microparts in a Multi-Station Former 836

H.W. Hoffmeister, H. Herrmann
Fine Grinding of Optical Glasses with Diamond Foil Tools 840

H. Suzuki, T. Higuchi, O. Horiuchi, H. Shibutani
Precision Cutting of Micro None-Axi-Symmetric Aspherical Surface with 3-Axes Controlled Diamond Tool 844

Y. Landon, P. Lagarrigue, F. Monies, W. Rubio
Correction of Circularity Defects on a N.C. Machine Tool 848

P. Dario, A. Eisenberg, A. Menciassi, C. Stefanini, G. Scalari, M.C. Carrozza
A sensorized µelectro discharge machined, superelastic alloy microgripper for micromanipulation 852